

Key
Lift-Off Layer: ■ **Permanent Use:** ○
Sacrificial Layer: △ **Lithographic Layer:** □

Device or Application	Product Line			
	PMGI	SU-8	PMMA	KMPR
Click on a symbol below for more information				
Compound Semi/Opto-Electronics				
HBTs	■			
PHEMT	■		■	
T-Gates	■		■	
VCSELs				
Microlens				
LEDs/OLEDs		○		
Waveguides				
MR/GMR Heads	■			
Air-bridges	△			
Wafer Thinning			△	
MEMS				
Polymeric	△	○		
C-MEMs (Pyrolysis)		○		
Inkjet Components				
3D-MEMS (electroplating molds)				△
Cantilevers		□		
Sensors				
Resonators				
Micro-fluidics	△	○		
Energy Devices				
Fuel cells				
Photo-voltaics				
Quantum Dots				
Advanced Lithographic Topics				
Soft-Litho (PDMS Mold)		○		
Surface Modification		○		
Grey -Scale				
Nano-Imprint				
Si Micromachining				□